



**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Mikihiko ISHII et al.

Group Art Unit: 2877

Application No.: 10/802,840

Examiner: M. LYONS

Filed: March 18, 2004

Docket No.: 119132

For: METHOD AND APPARATUS FOR POINT DIFFRACTION INTERFEROMETRY

**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the February 9, 2005 Office Action, the shortened statutory period for reply being extended by the attached Petition for Extension of Time, please consider the following:

**Amendments to the Specification;**

**Amendments to the Claims** as reflected in the listing of claims;

**Amendments to the Drawings** include an attached replacement sheet; and

**Remarks.**